

31000 U.S. PTO

10/058426

01/30/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10058426	01/30/2002	430	311	1756	Barreca Barreca

**APPLICANTS: Komada Daisuke; Kakamu Katsumi;

CONTINUING DATA VERIFIED: *none* FOREIGN APPLICATIONS VERIFIED: *ny*

JAPAN 2001-312883 10/10/2001

BEST AVAILABLE COPY

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO
Foreign priority claimed <i>ny</i> yes <input checked="" type="checkbox"/> no <input type="checkbox"/>			020060
35 USC 119 conditions met <i>ny</i> yes <input checked="" type="checkbox"/> no <input type="checkbox"/>			
Verified and Acknowledged Examiners's initials <i>ny</i>			
TITLE : Method of manufacturing semiconductor device having silicon carbide film			

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
Assistant Examiner		Total Claims	Print Claim for O.G.
		DRAWING	
ISSUE FEE		Sheets Drwg.	Figs. Drwg.
Amount Due	Date Paid	Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Application Examiner	
		PREPARED FOR ISSUE	
WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368, Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.			

FILED WITH:

☐ DISK (CRF)☐ CD-ROM

(Attached in pocket on right inside flap)